

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Isamu Kobori et al. Art Unit : Unknown
Serial No. : New Divisional Application Examiner : Unknown
Filed : July 22, 2003
Title : METHOD OF MANUFACTURING A SEMICONDUCTOR METHOD OF
MANUFACTURING A THIN-FILM TRANSISTOR AND THIN-FILM
TRANSISTOR

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

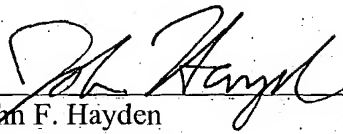
INFORMATION DISCLOSURE STATEMENT

Under 35 USC §120, this application relies on the earlier filing dates of application serial numbers 09/016,999, filed on February 2, 1998 and 08/623,506, filed on March 28, 1996. The attached list of references were submitted to and/or cited by the Office in the prior application and, therefore, are not provided in this application.

This statement is being filed with the application. Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: July 22, 2003



John F. Hayden
Reg. No. 37,640

Fish & Richardson P.C.
1425 K Street, N.W.
11th Floor
Washington, DC 20005-3500
Telephone: (202) 783-5070
Facsimile: (202) 783-2331

Substitute Form PTO-1449 (Modified) Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 07977-024003	Application No. New Divisional Application
	Applicant Isamu Kobori et al.		
	Filing Date July 22, 2003	Group Art Unit Unknown	

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	5,413,958	05/1995	Imahashi et al.			
	AB	5,529,630	06/1996	Imahashi et al.			
	AC	5,595,923	01/1997	Zhang et al.			
	AD	5,767,930	06/1998	Kobayashi et al.			
	AE	5,854,494	05/1995	Yamazaki et al.			
	AF	5,966,594	10/1999	Adachi et al.			
	AG	5,854,096	12/1998	Ohtani et al.			
	AH	5,712,191	01/1998	Nakajima et al.			
	AI	5,731,613	03/1998	Yamazaki et al.			
	AJ	5,937,282	08/1999	Nakajima et al.			
	AK	5,959,313	09/1999	Yamazaki et al.			
	AL	6,051,453	04/2000	Takemura			
	AM	6,071,764	06/2000	Zhang et al.			

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AN	05,009,089 A	01/1993	Japan				
	AO	01-222432	09/1989	Japan				
	AP	06-260643	09/1994	Japan				

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AQ	Y. Fukushima et al.; "A Poly-Si TFT Process for High Speed and Low Voltage CMOS Circuits"; <i>Extended Abstracts of the 1993 International Conference on Solid State Devices and Materials, Makuhari</i> ; pp. 993-995; 1993
	AR	
	AS	
	AT	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	